

FIG. 1 PRIOR ART

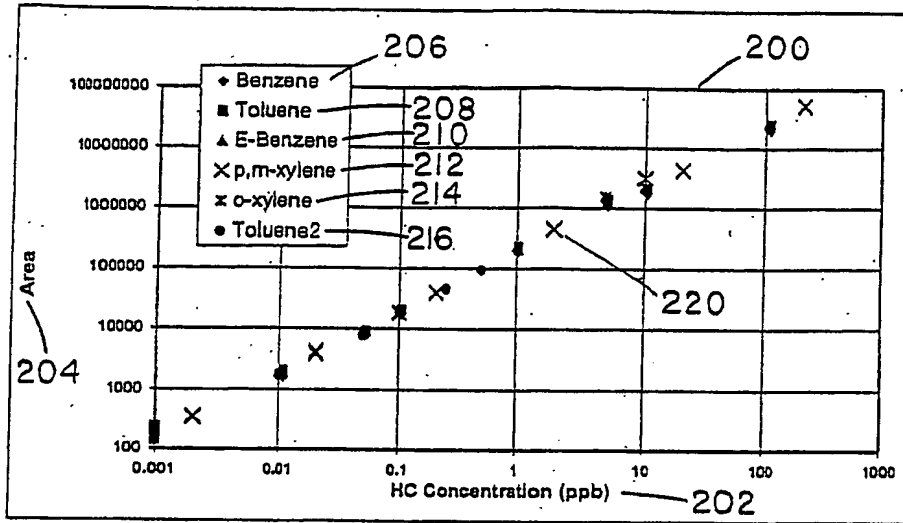


FIG. 2 PRIOR ART

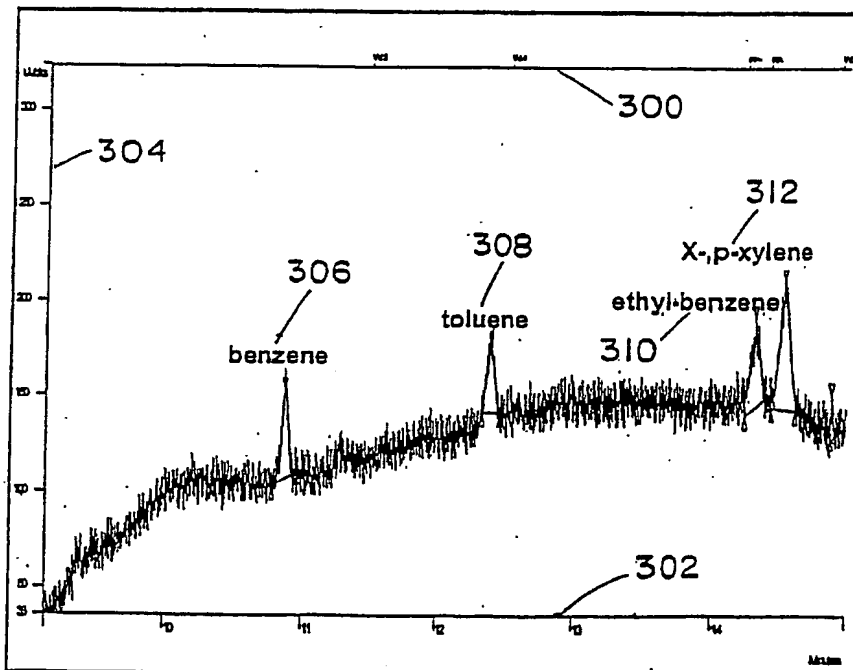


FIG. 3 PRIOR ART

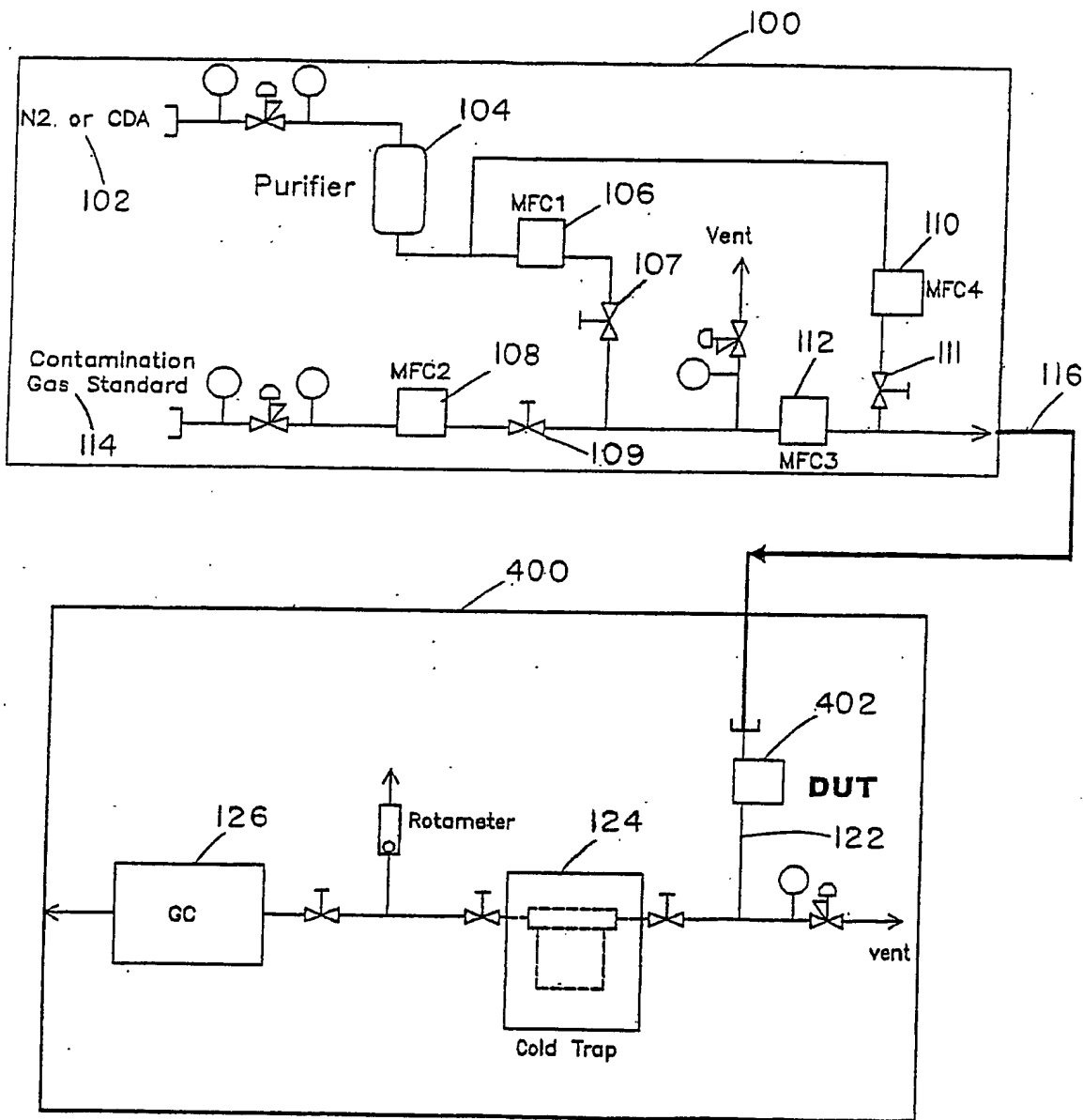
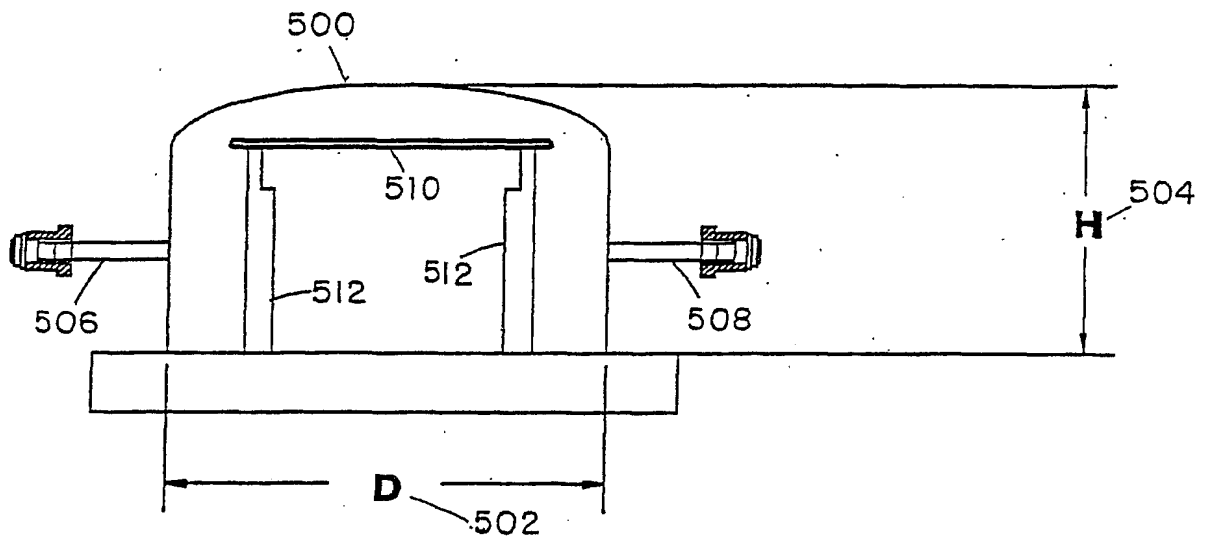


FIG. 4



Wafer Chamber

FIG. 5

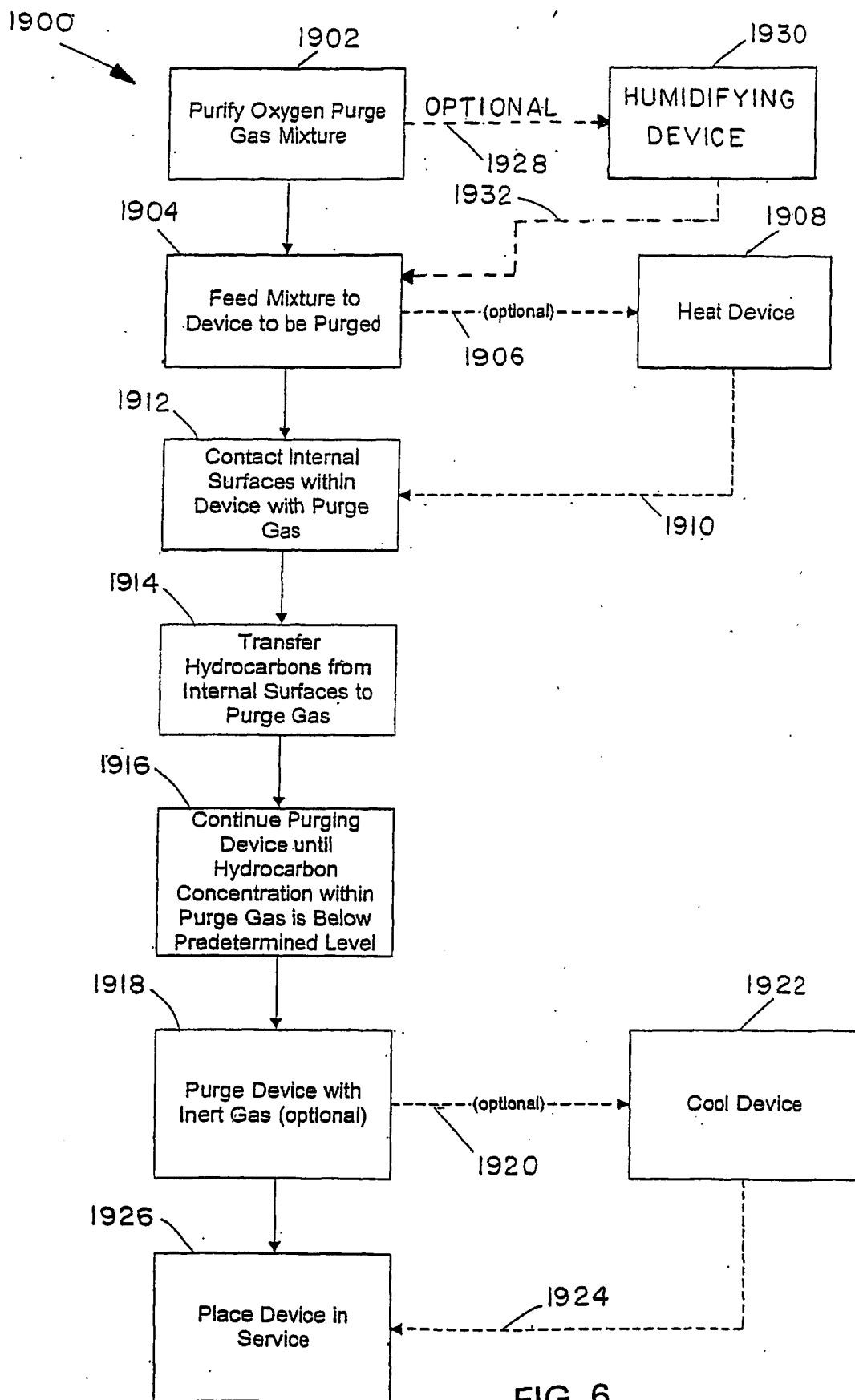


FIG. 6

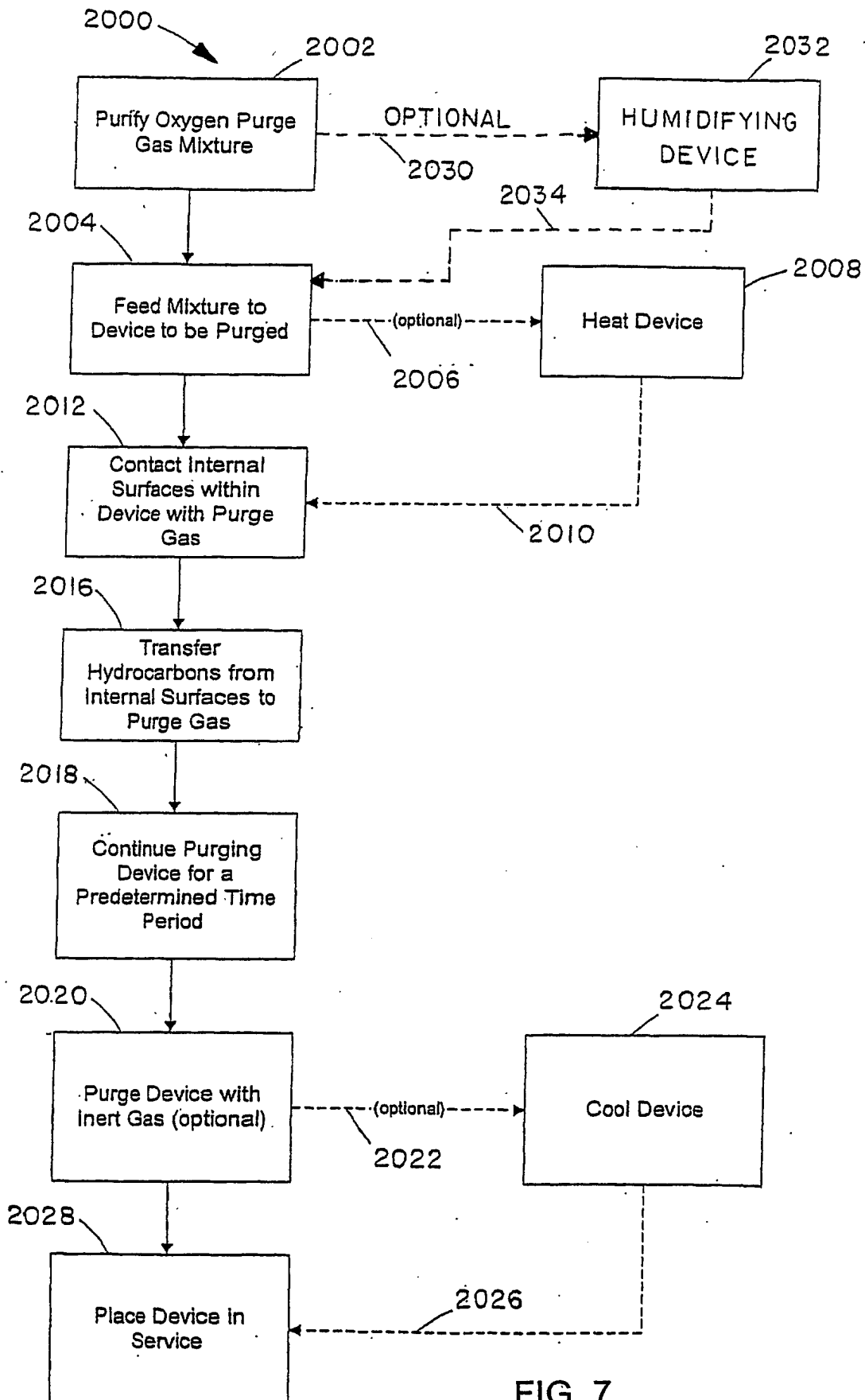


FIG. 7

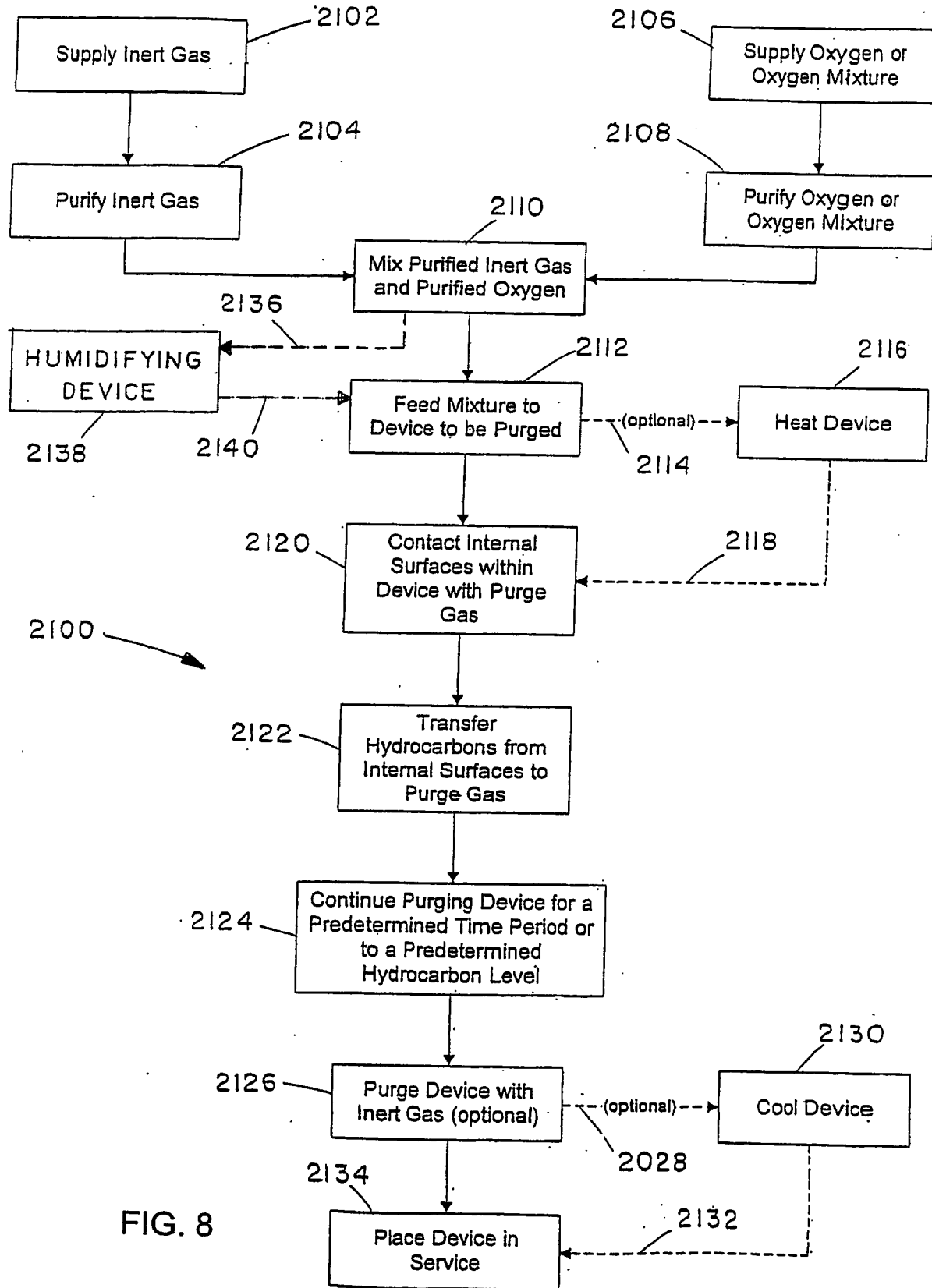


FIG. 8

8/29

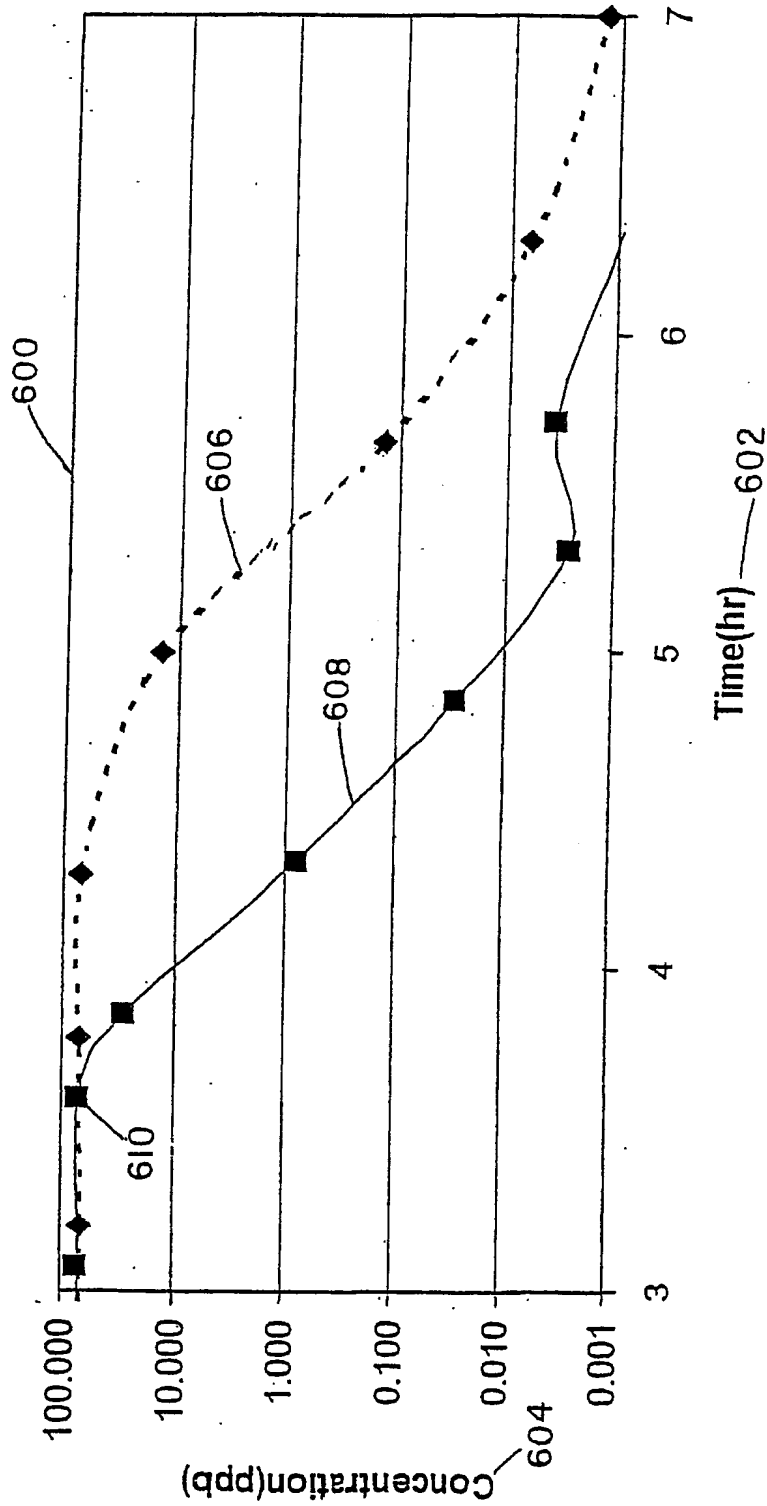


FIG. 9



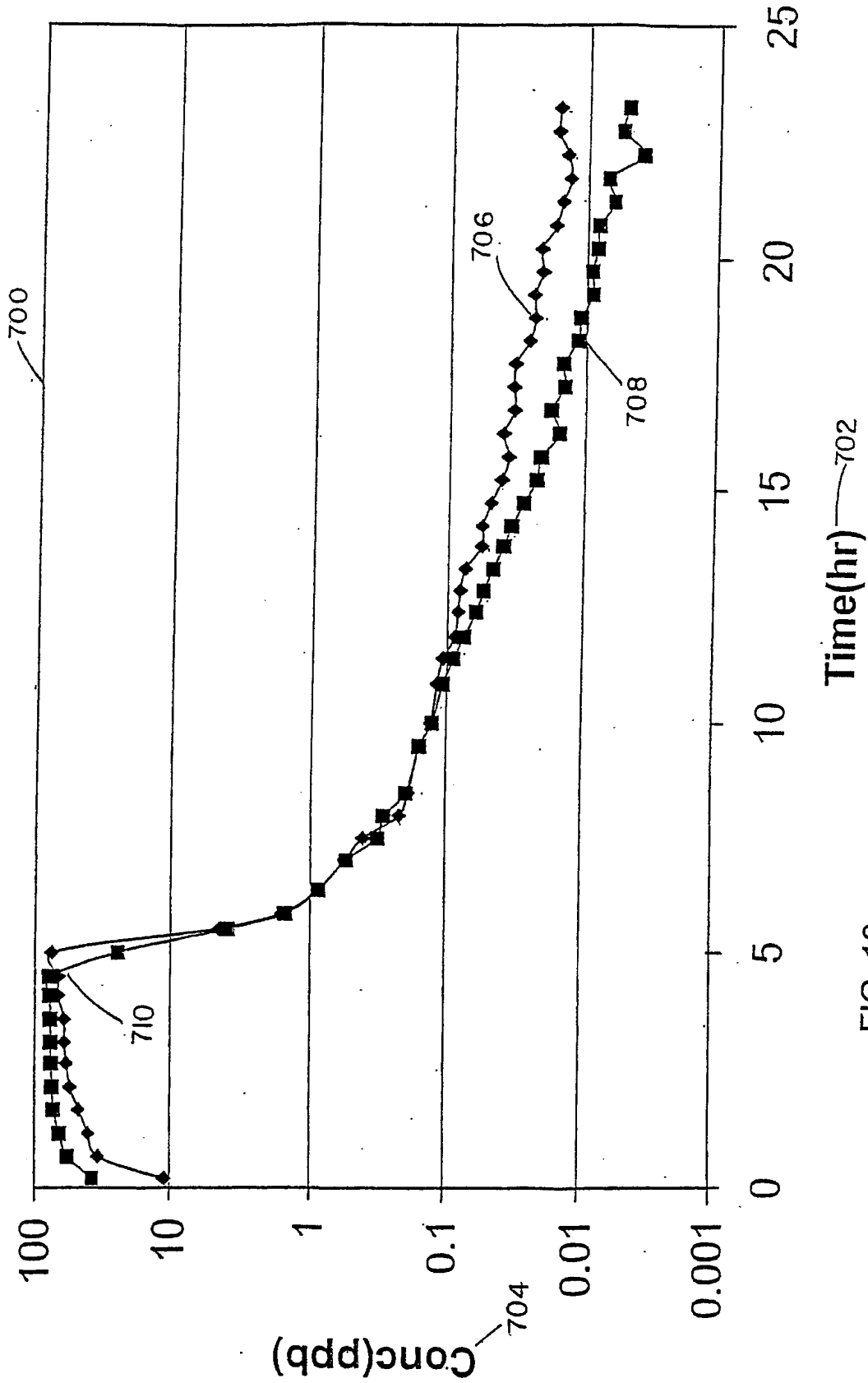


FIG. 10

10/29

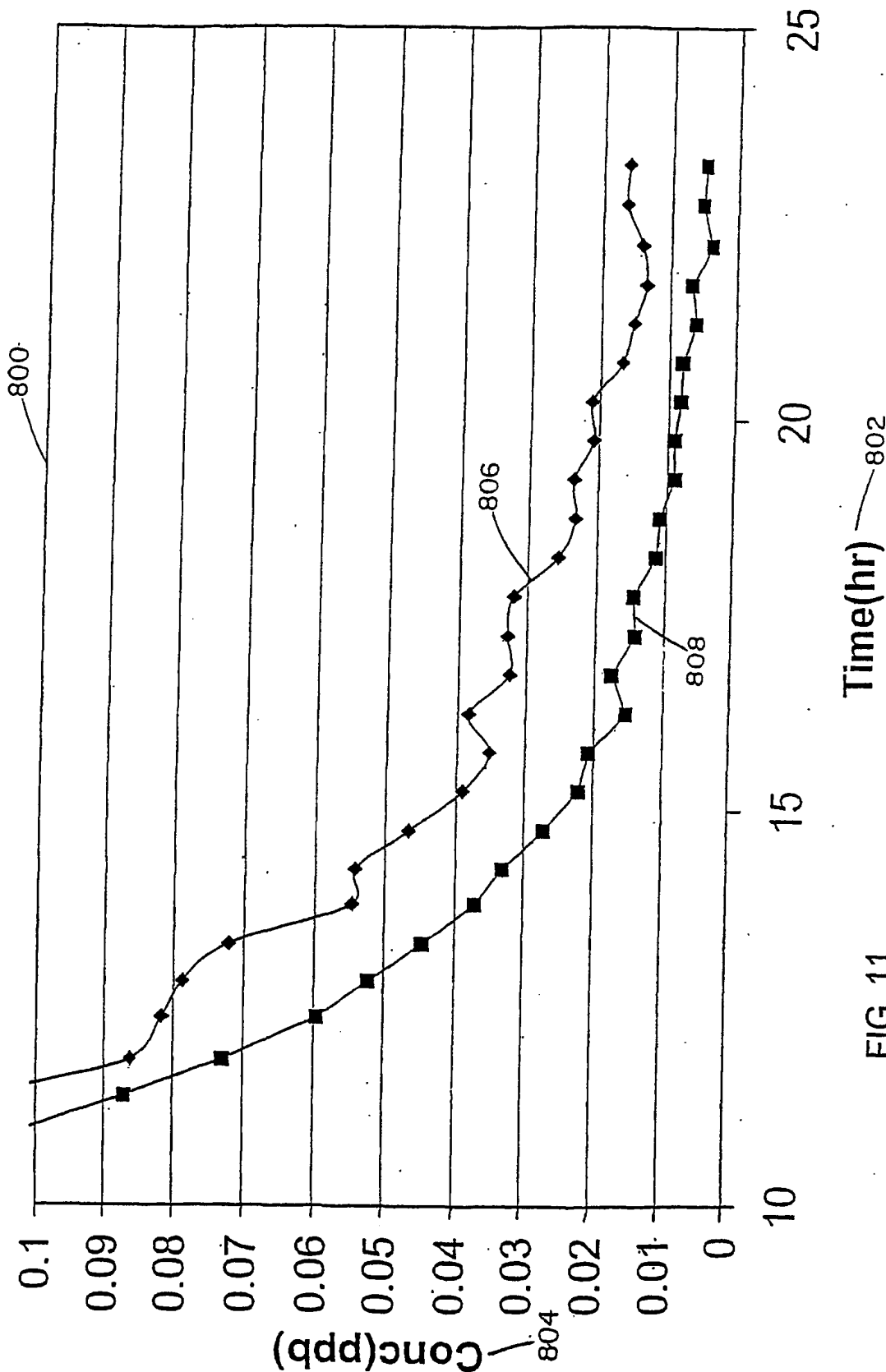


FIG. 11

11/29

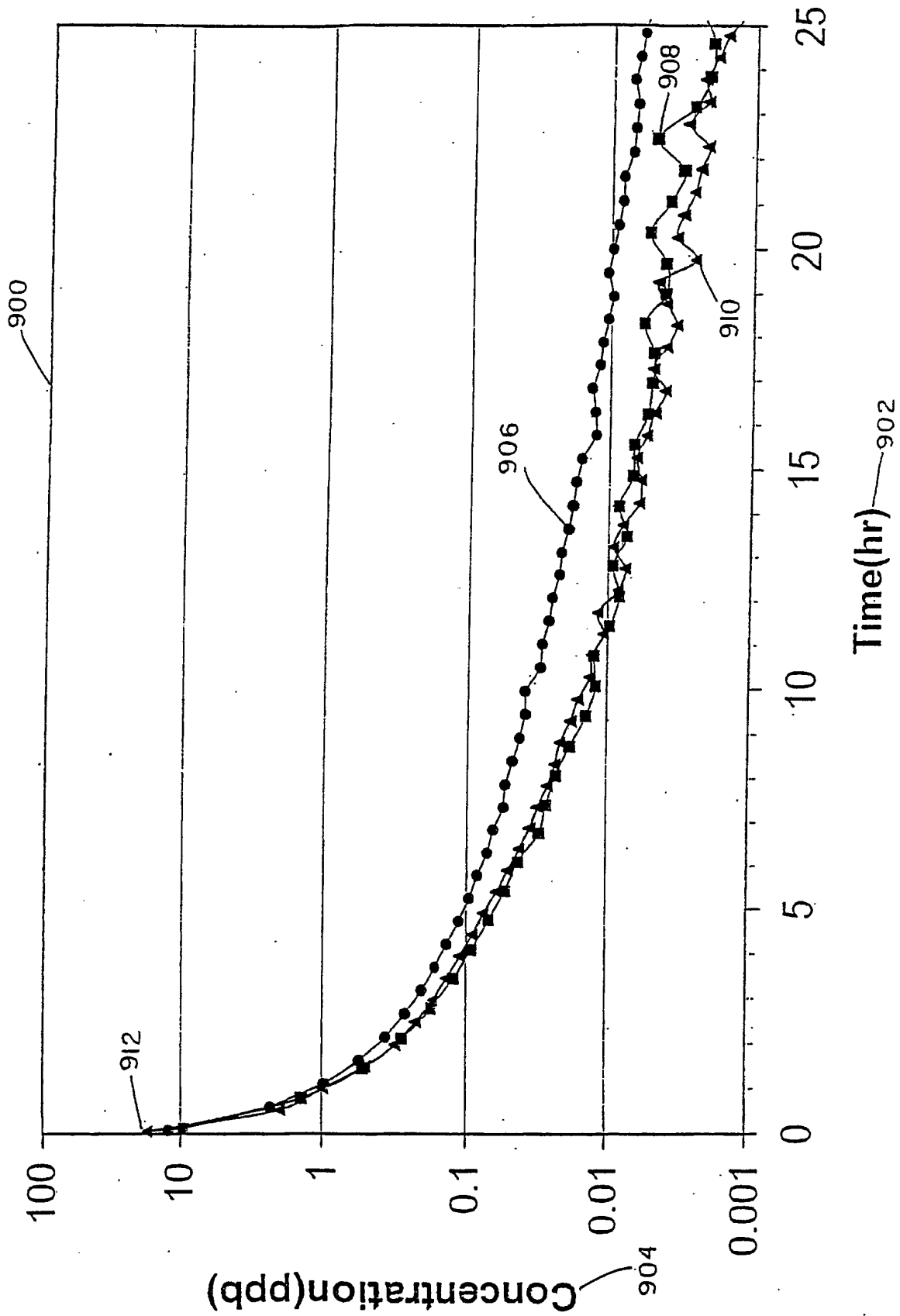


FIG. 12

12/29

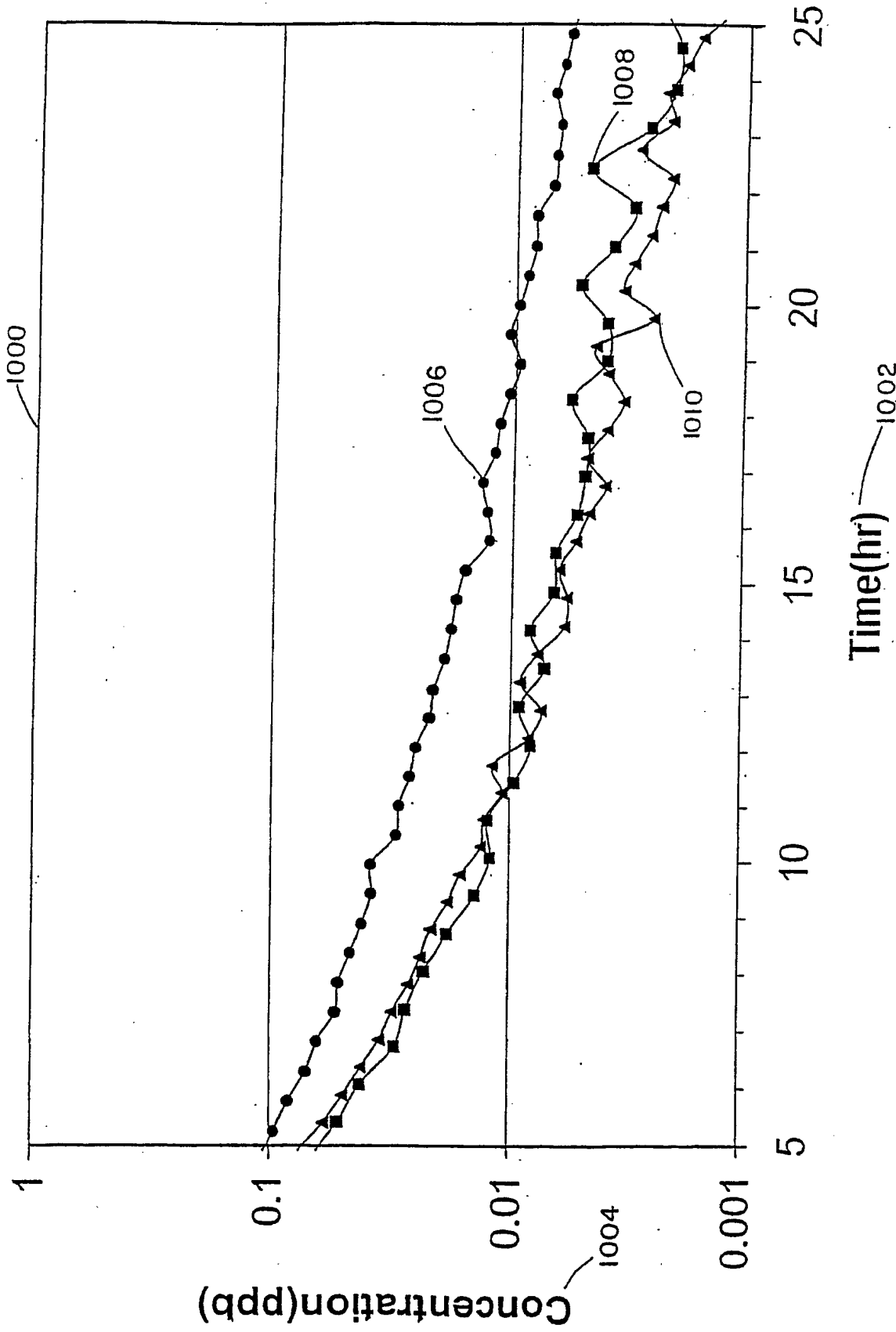


FIG. 13

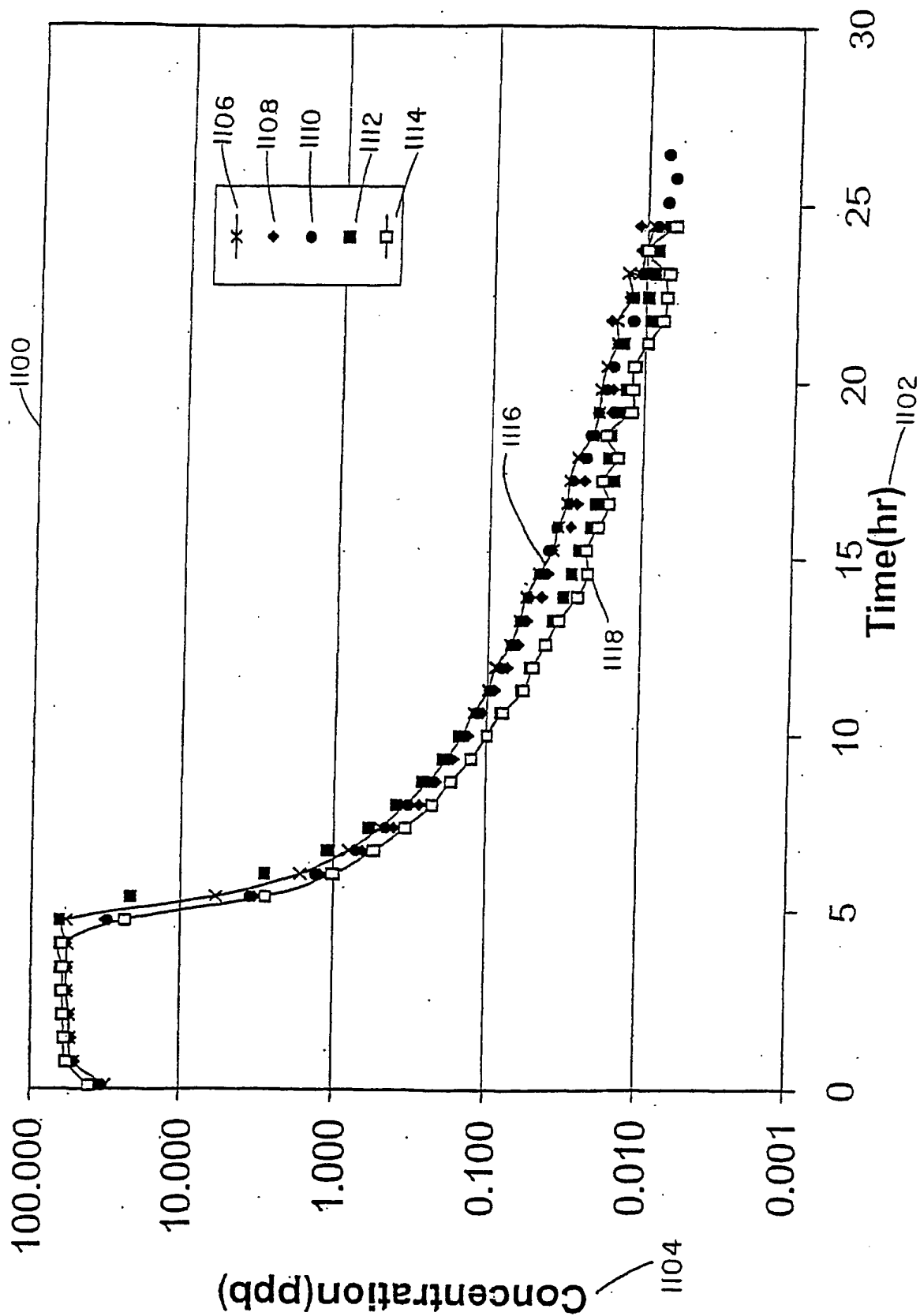


FIG. 14

14/29

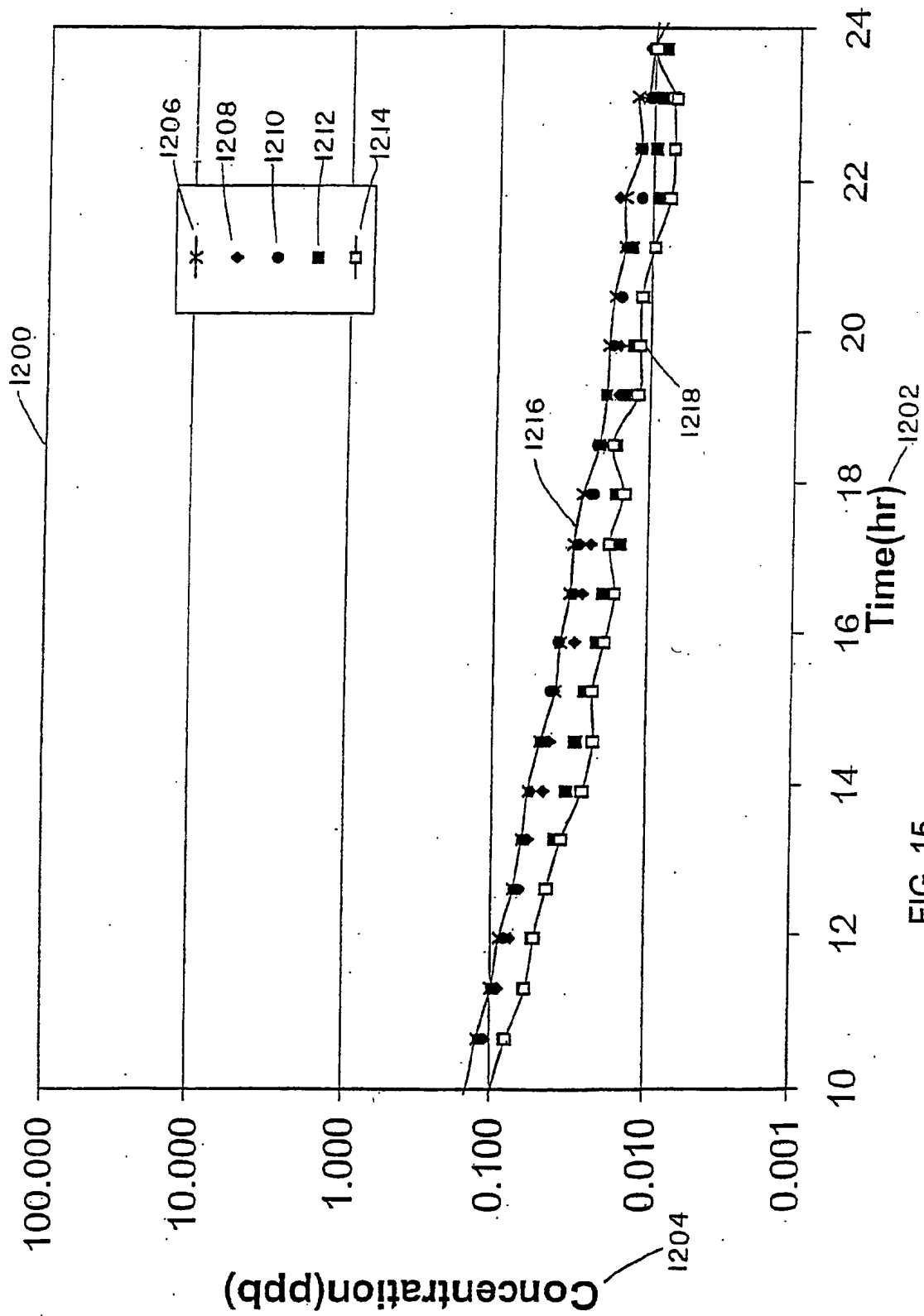


FIG. 15

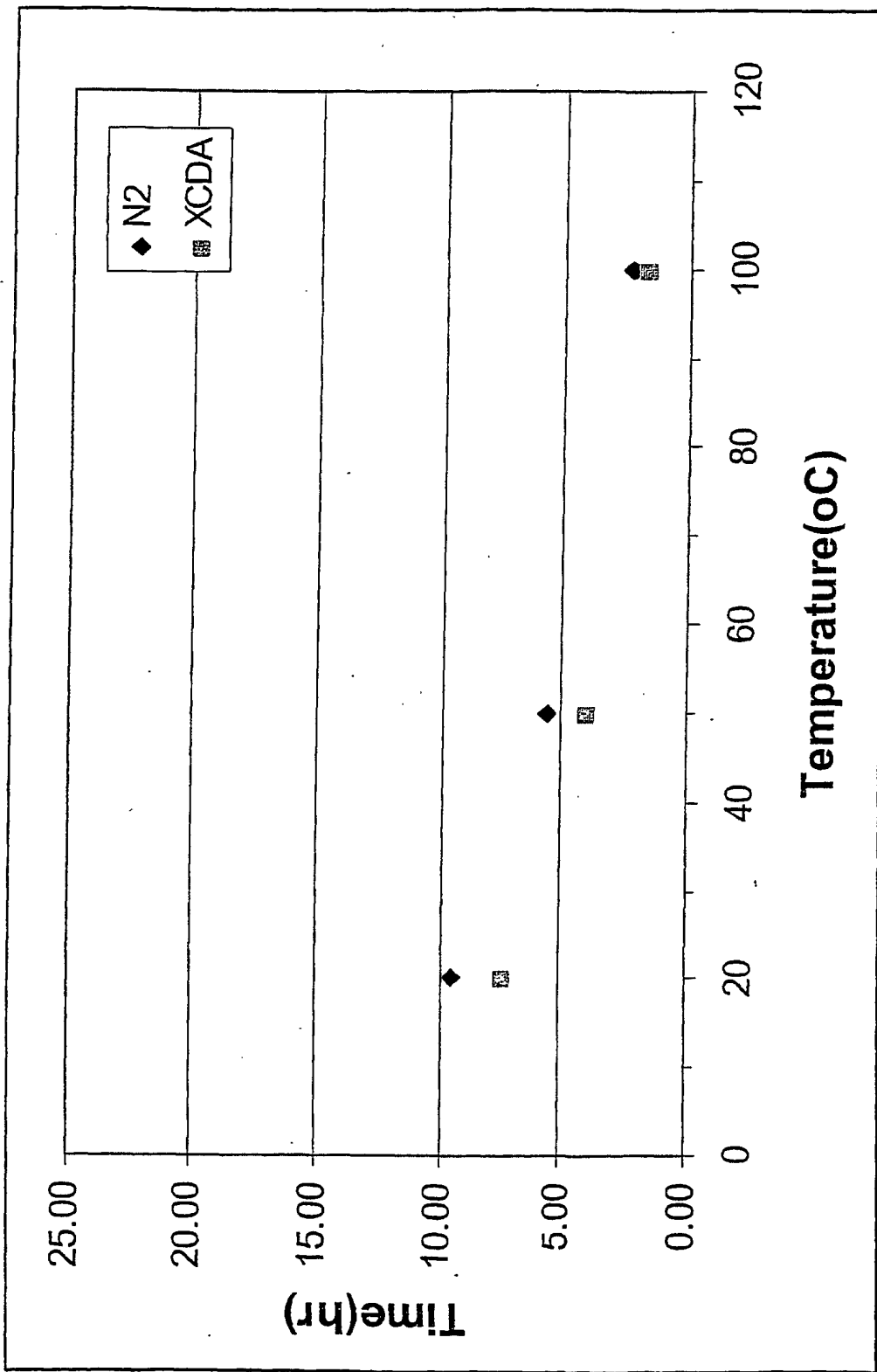


FIG. 16

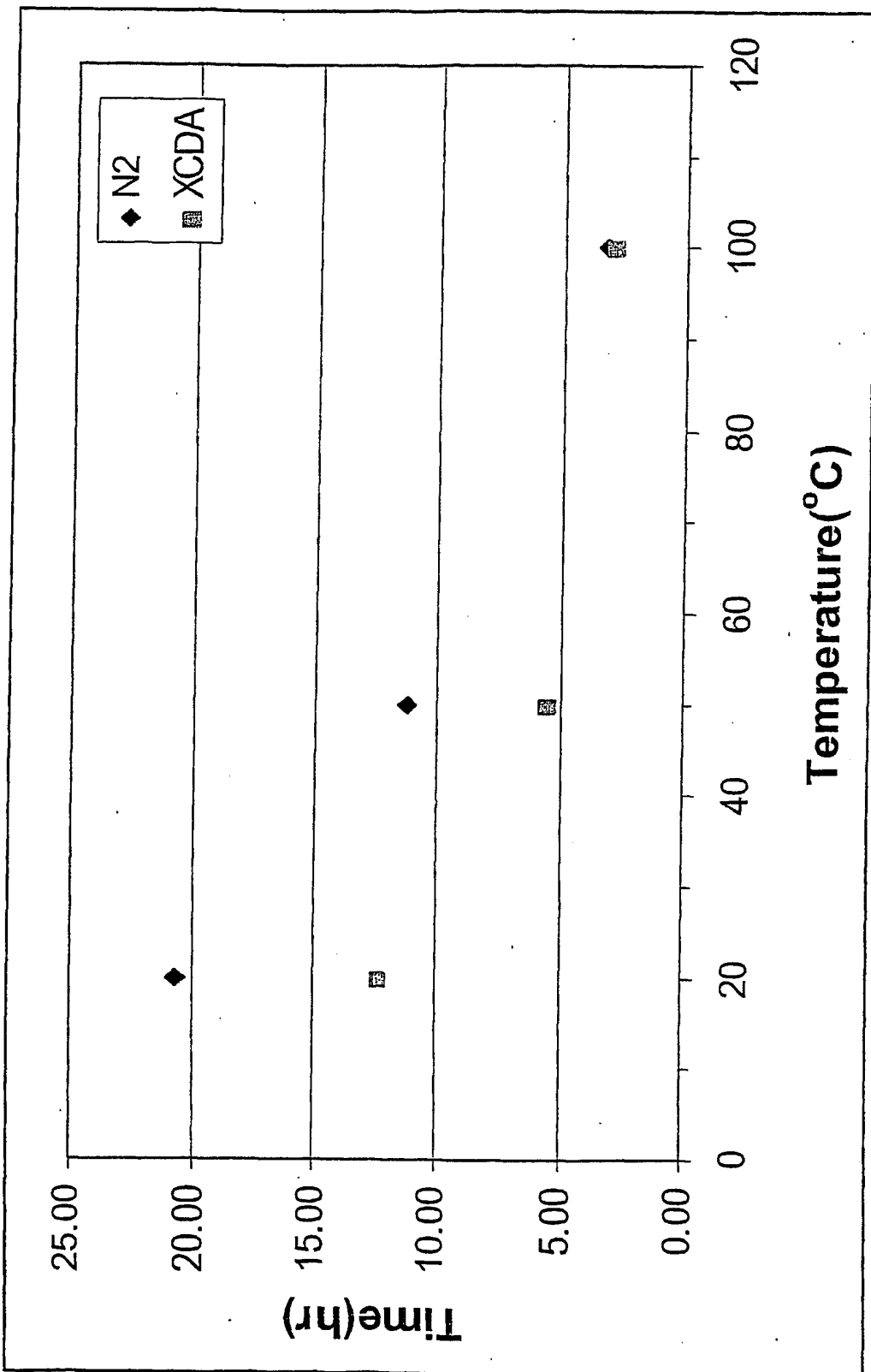


FIG. 17



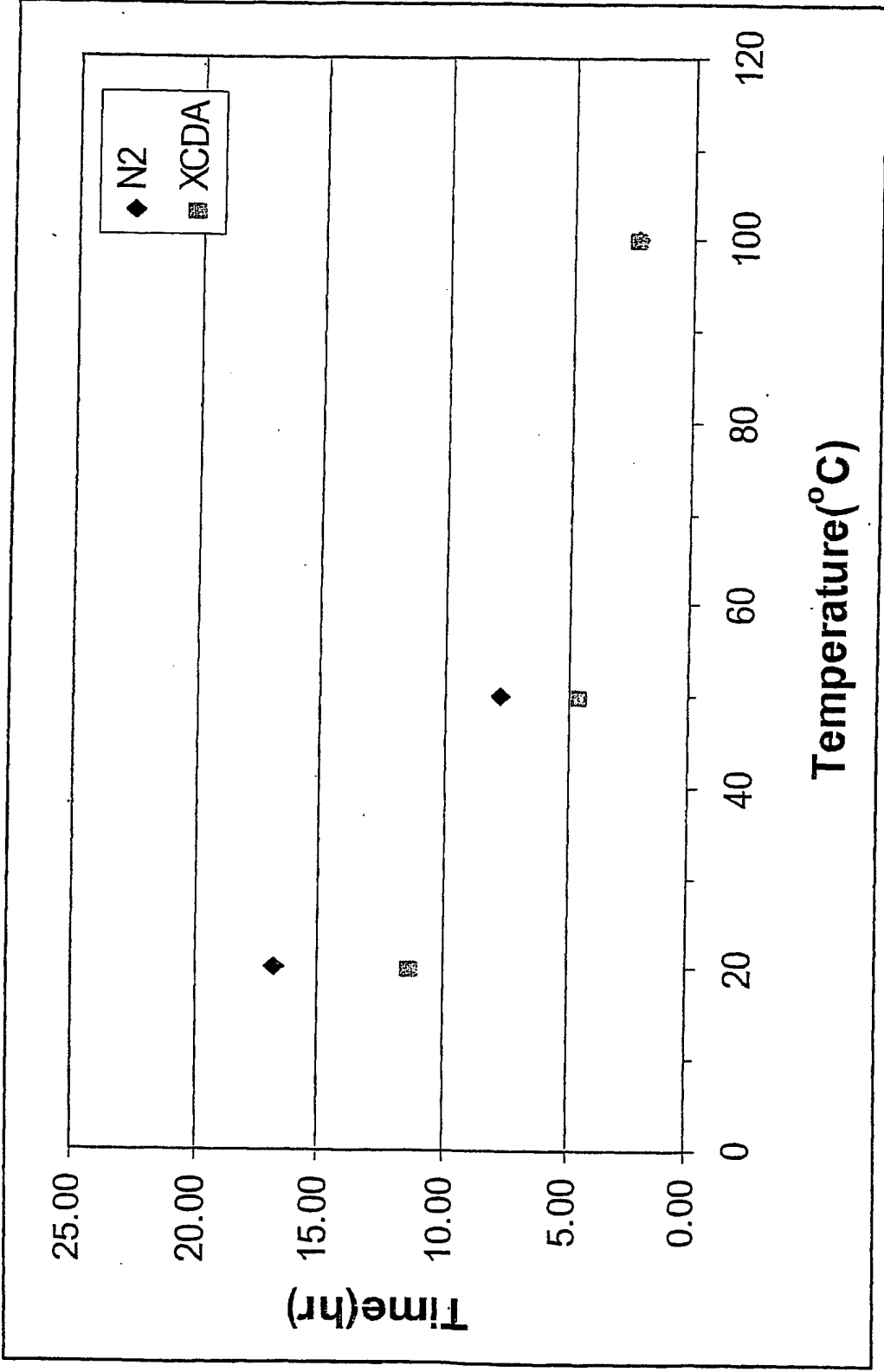


FIG. 18

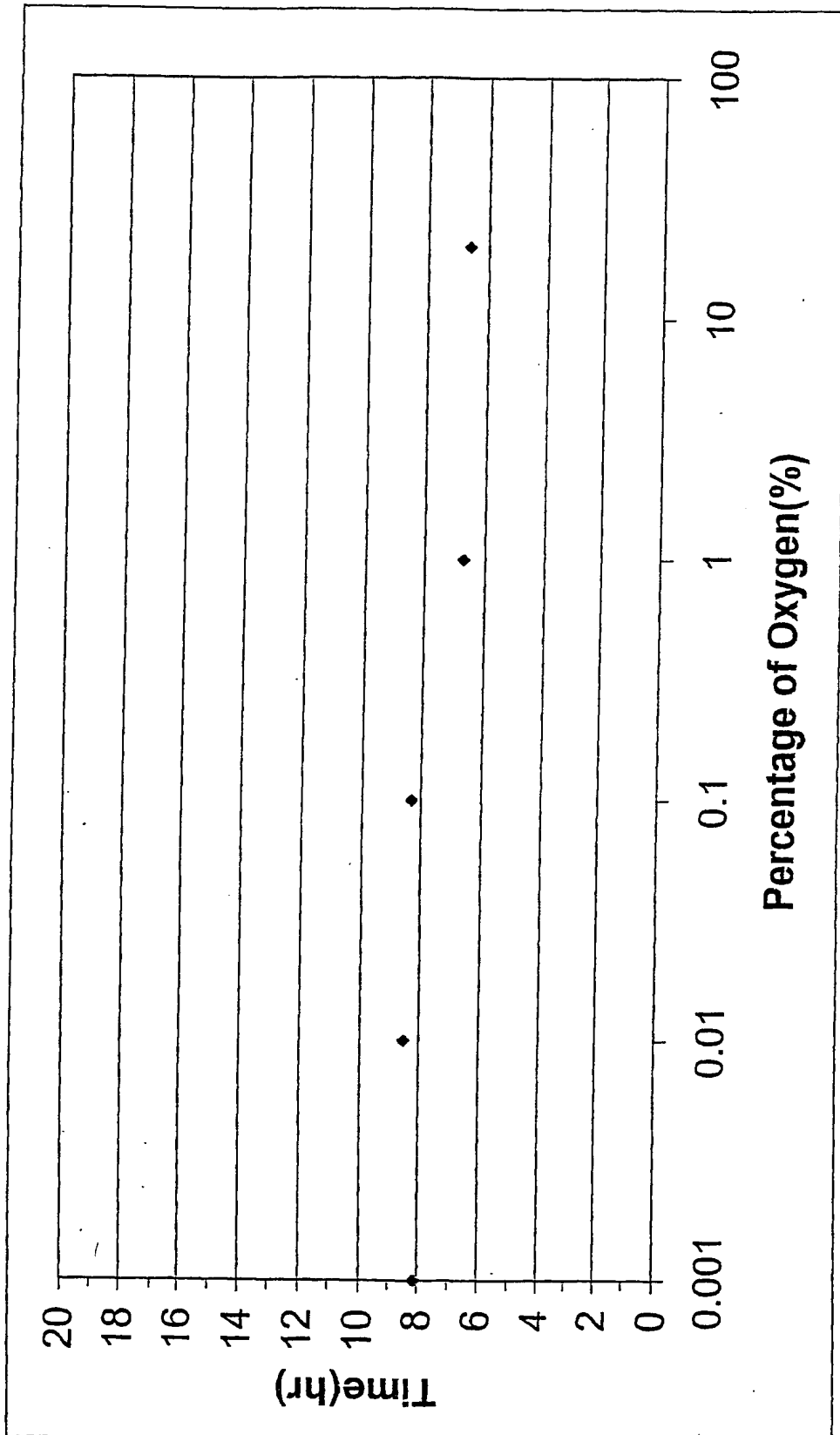


FIG. 19

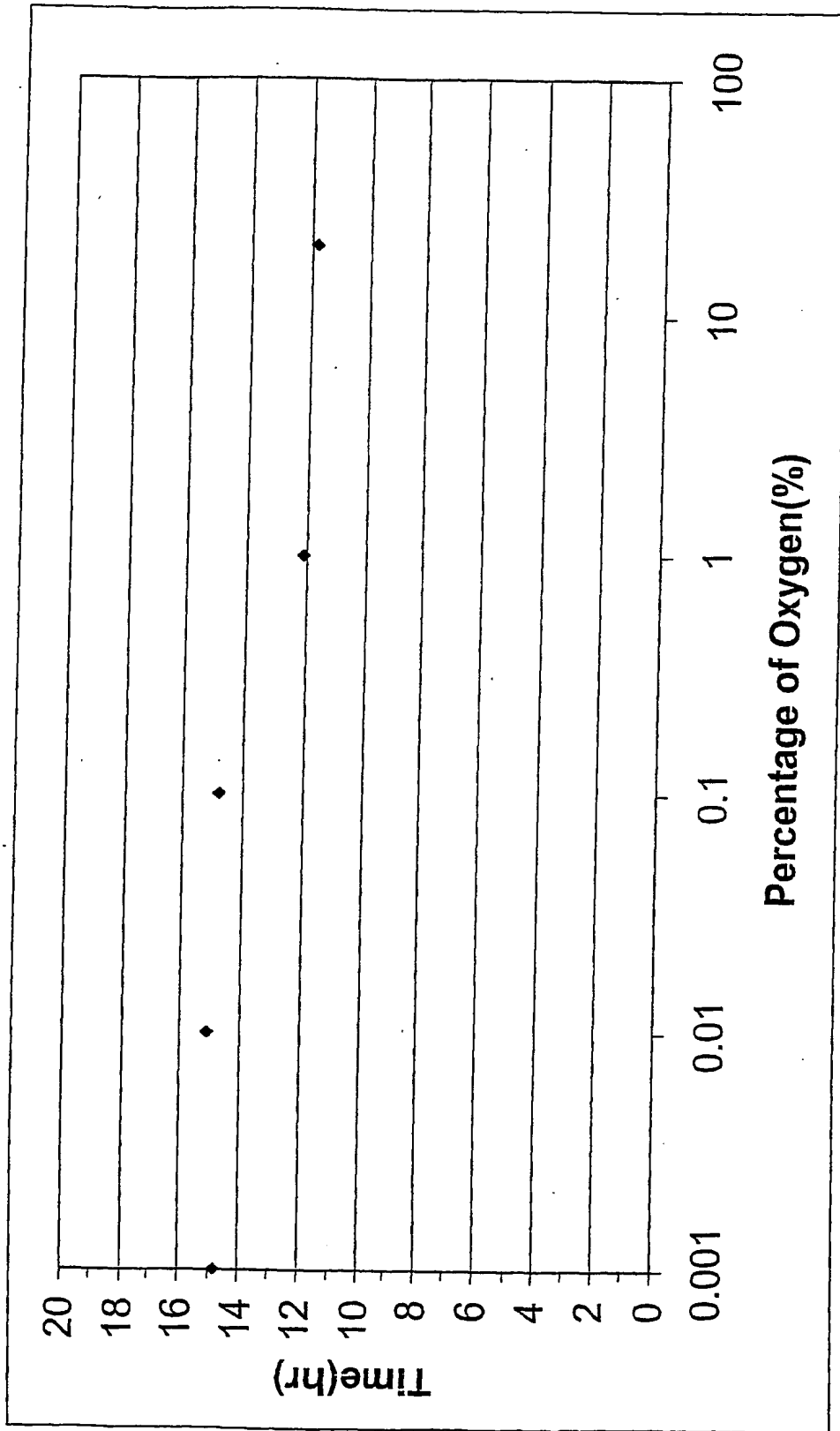


FIG. 20

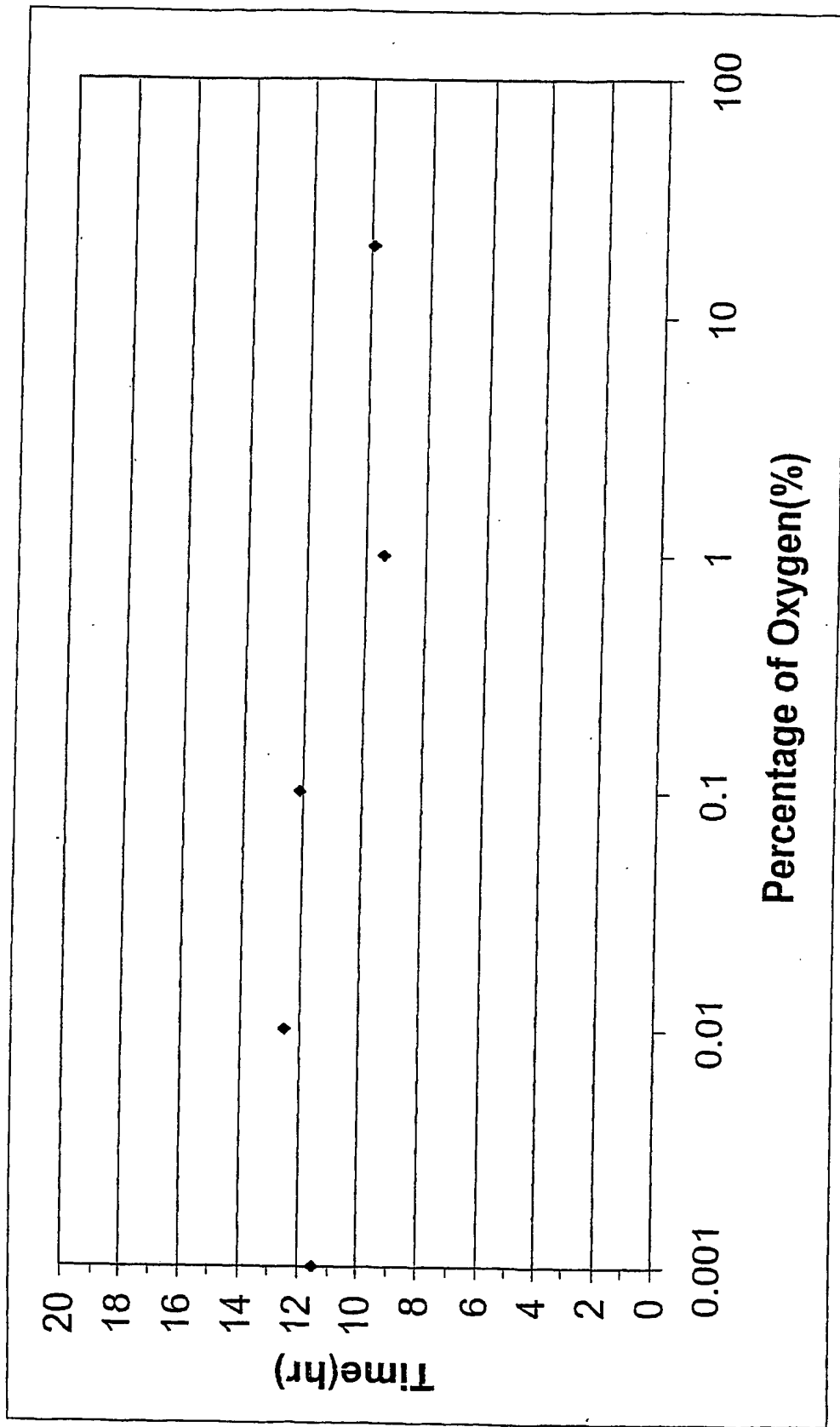


FIG. 21

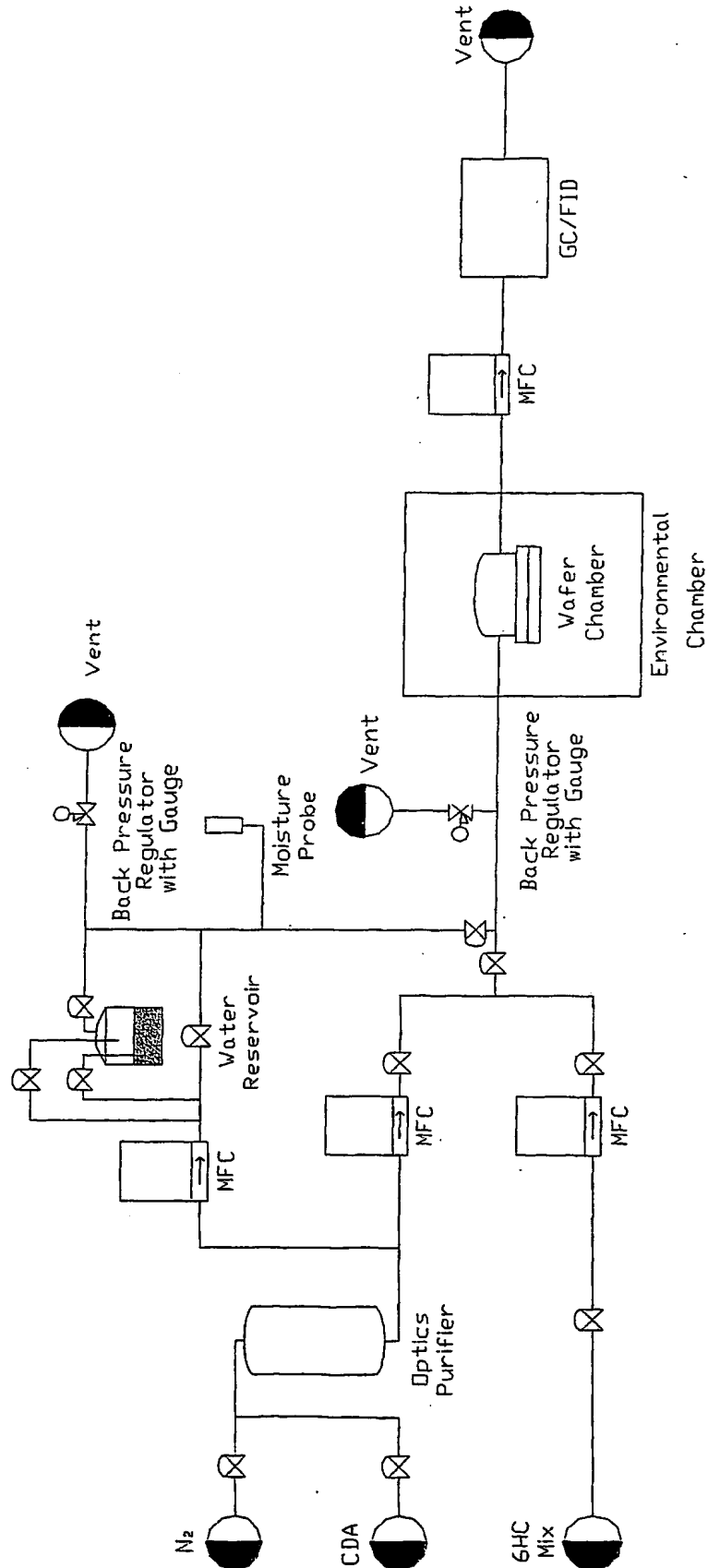


FIG. 22

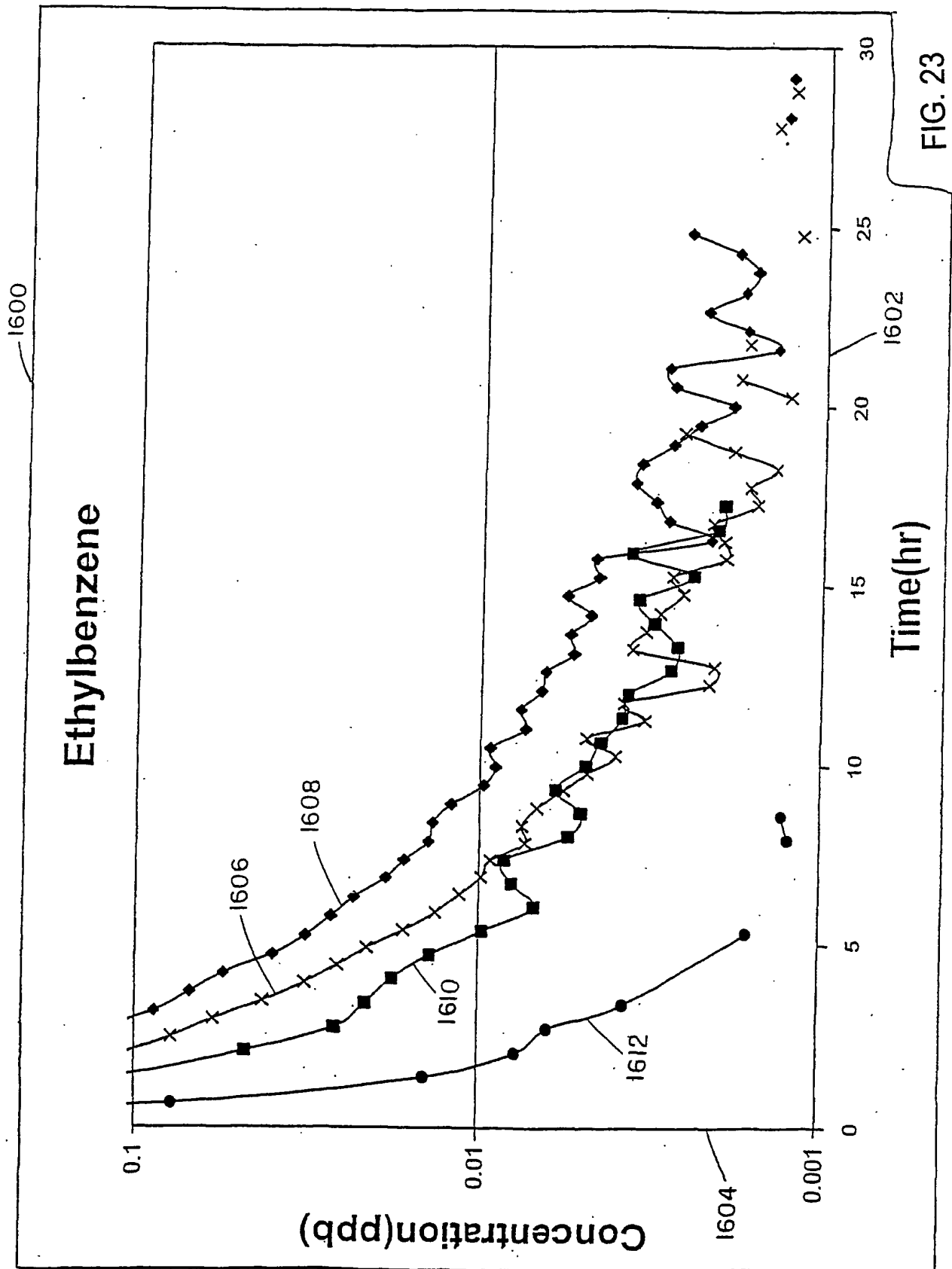


FIG. 23

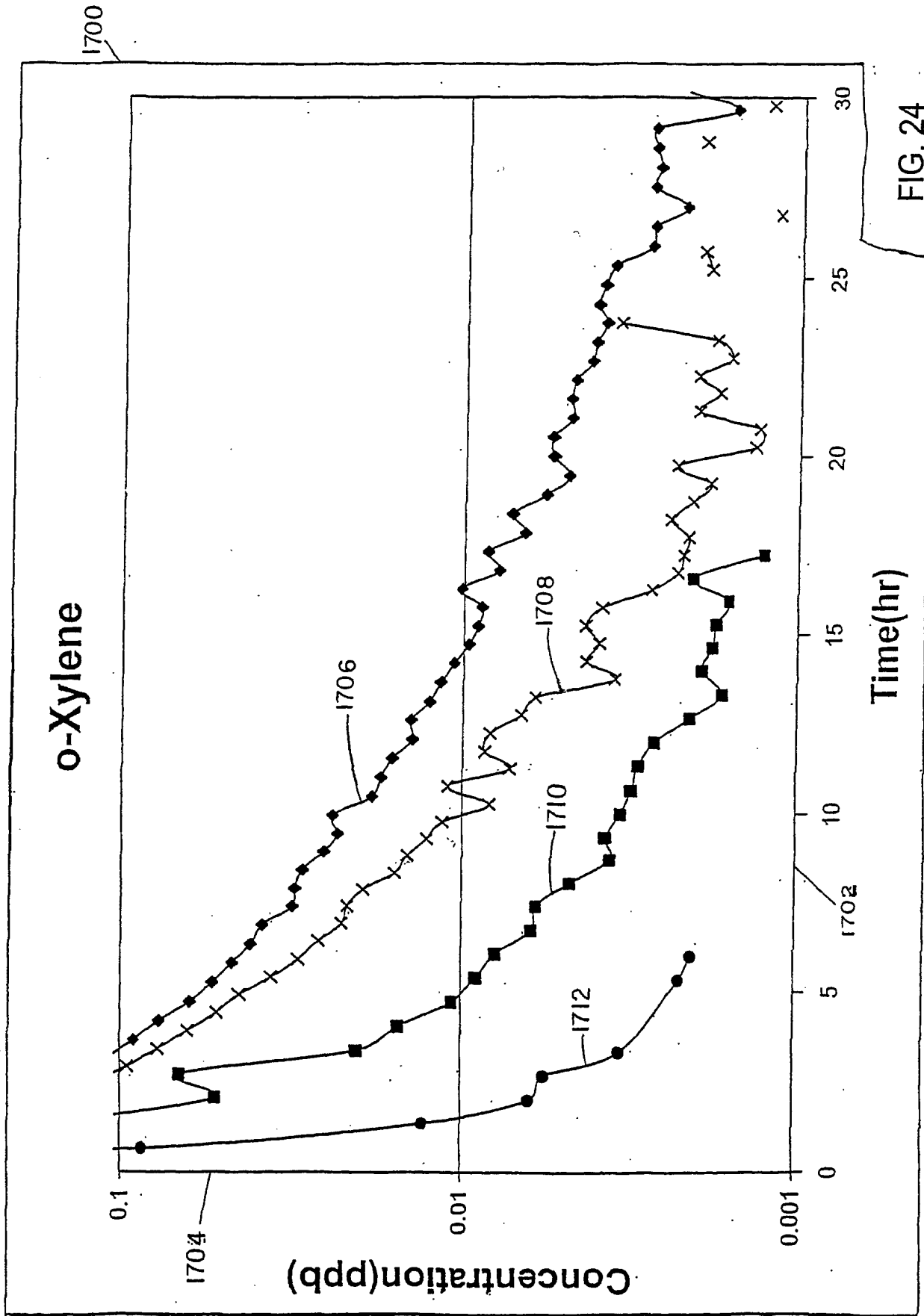


FIG. 24

24/29

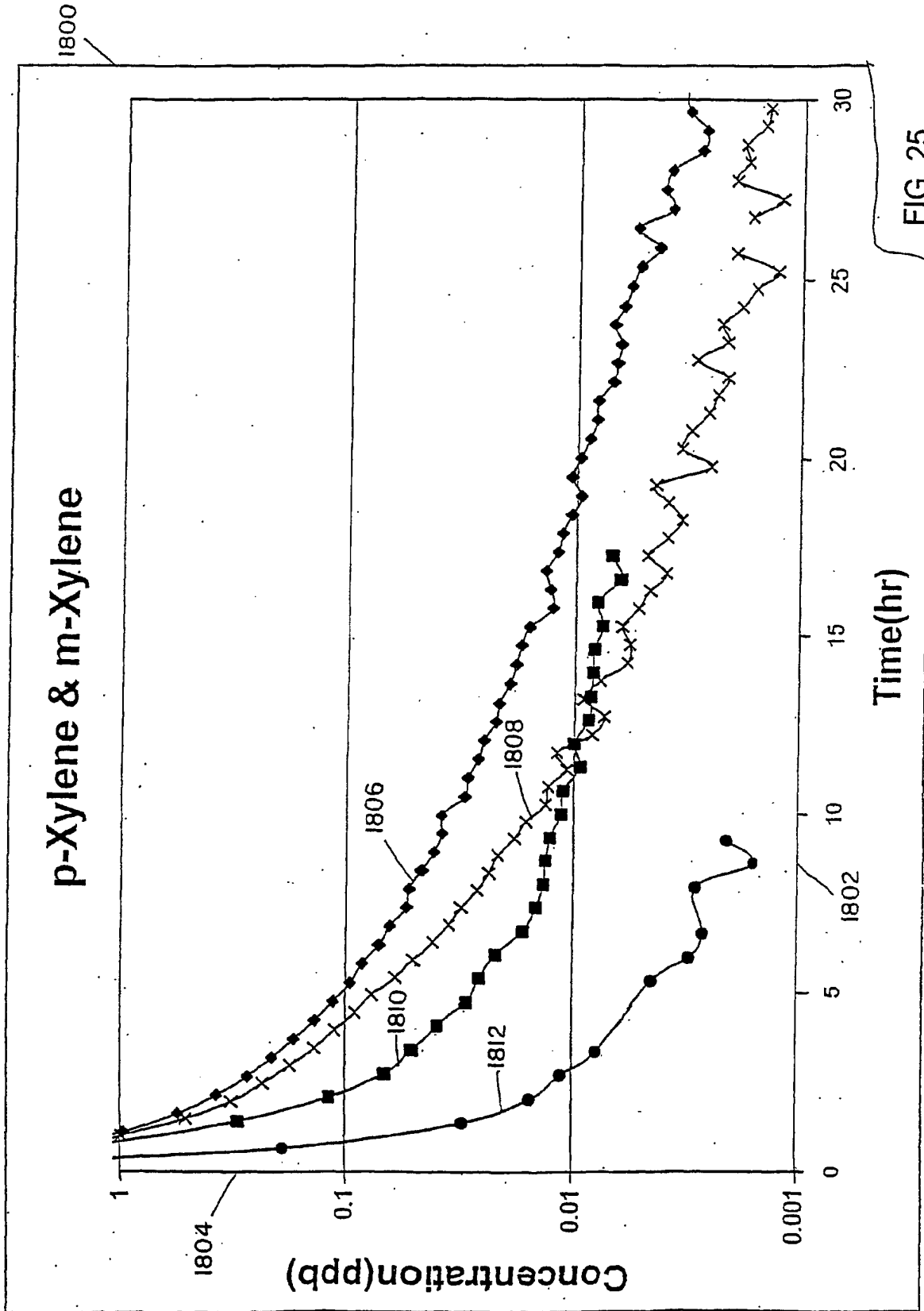


FIG. 25



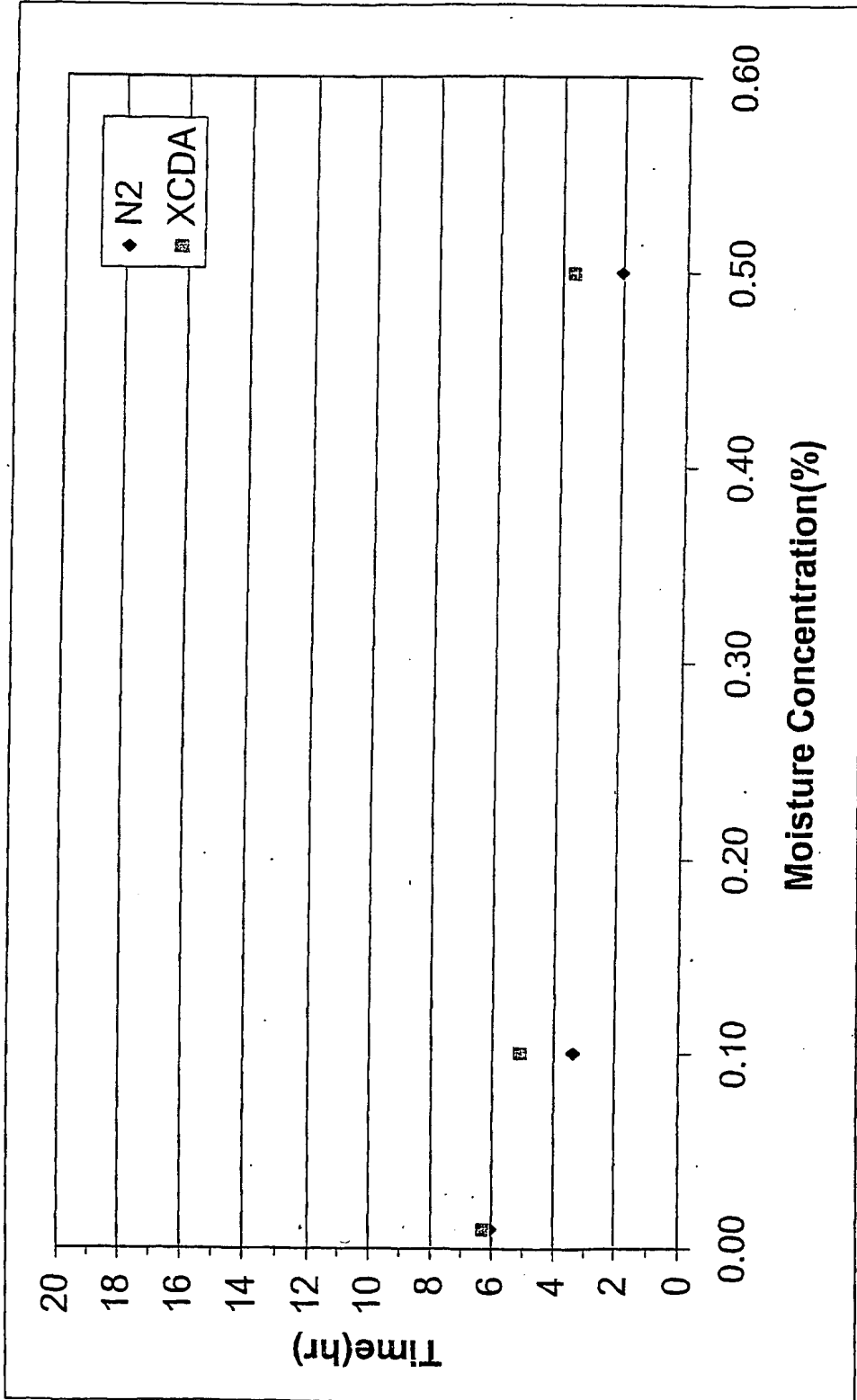


FIG. 26

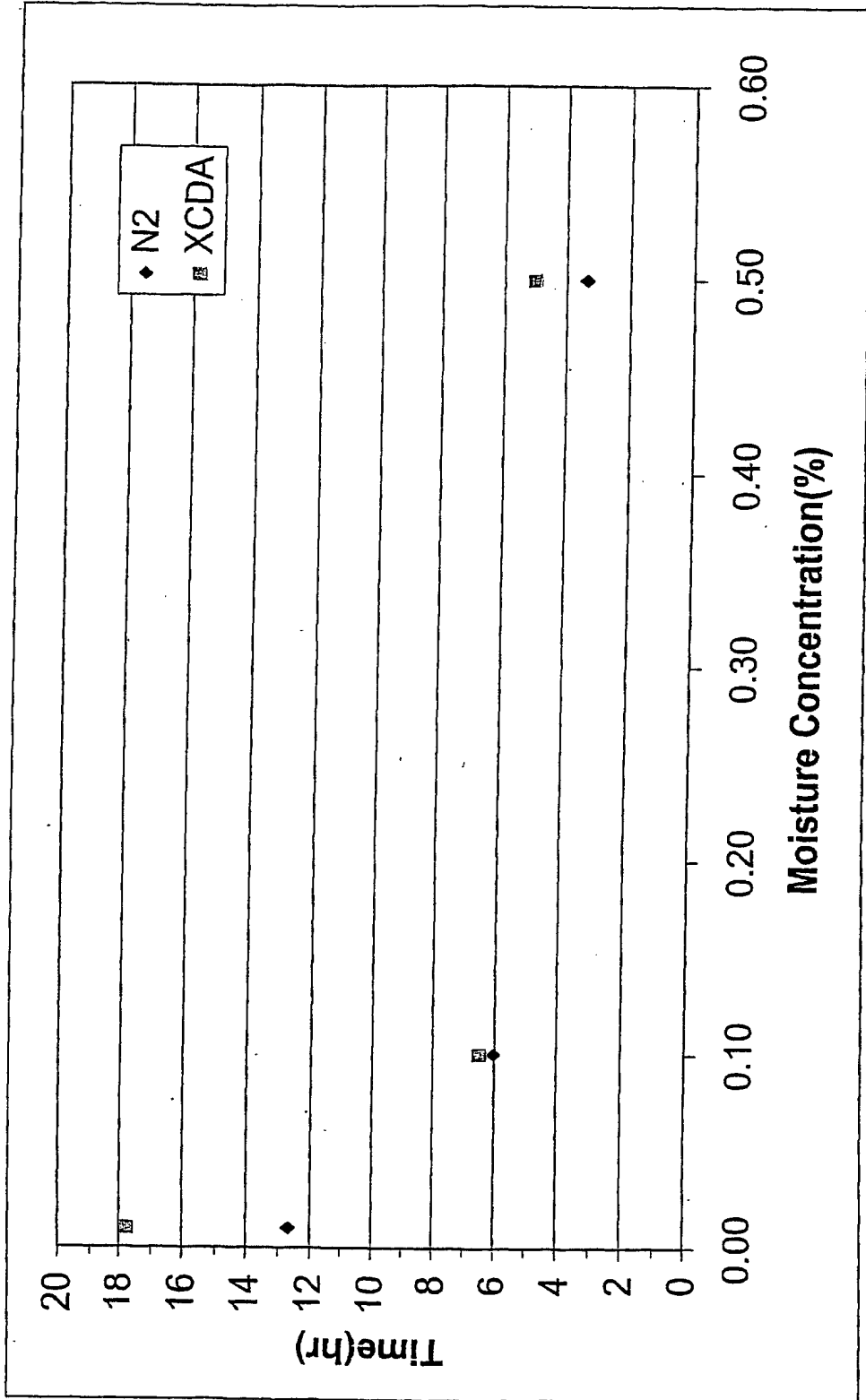


FIG. 27

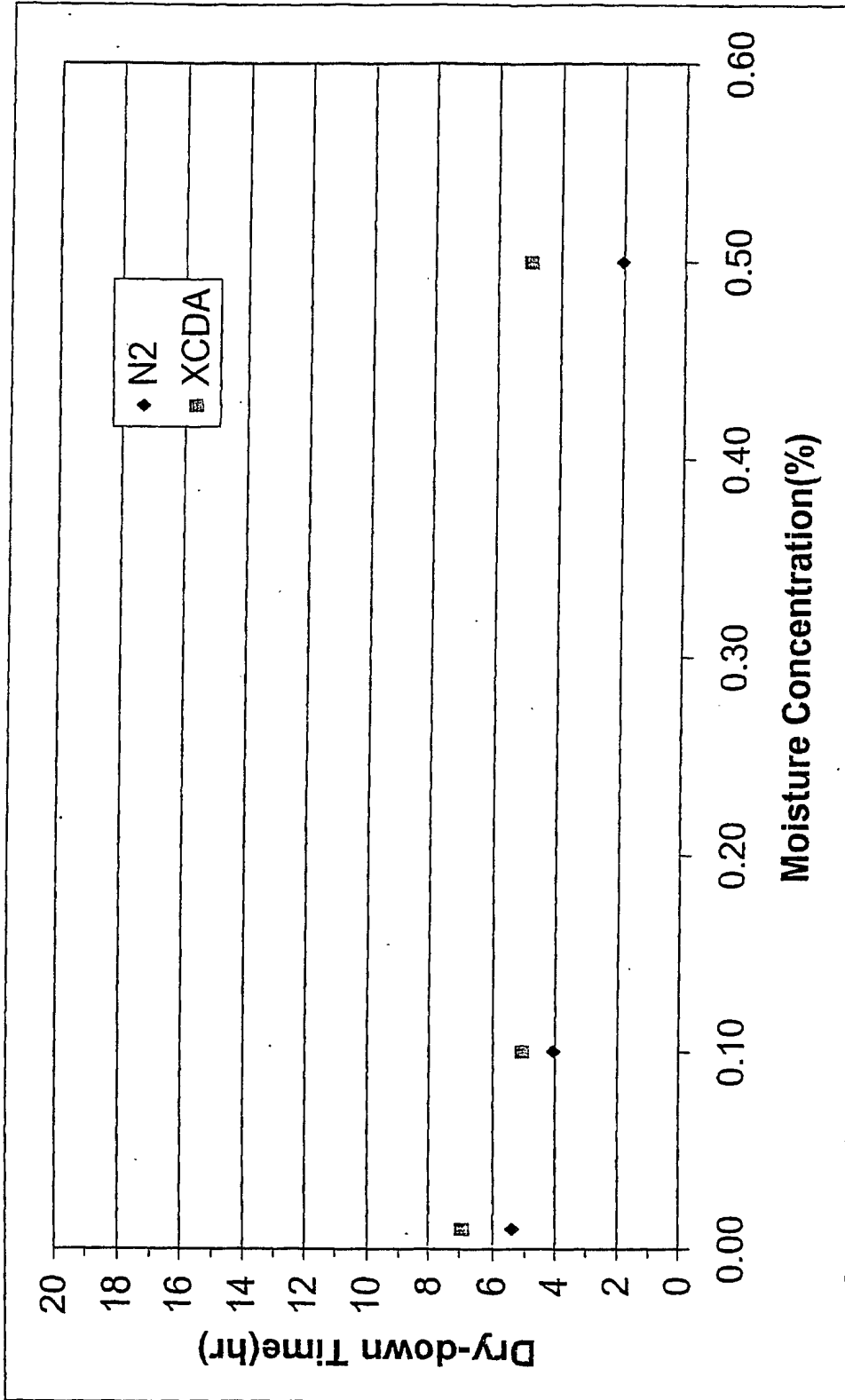


FIG. 28

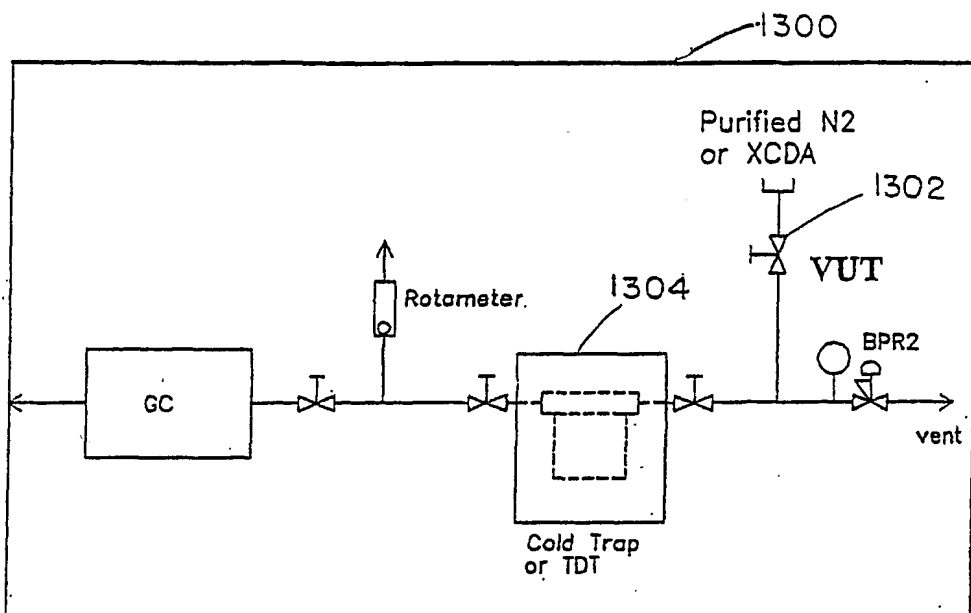


FIG. 29

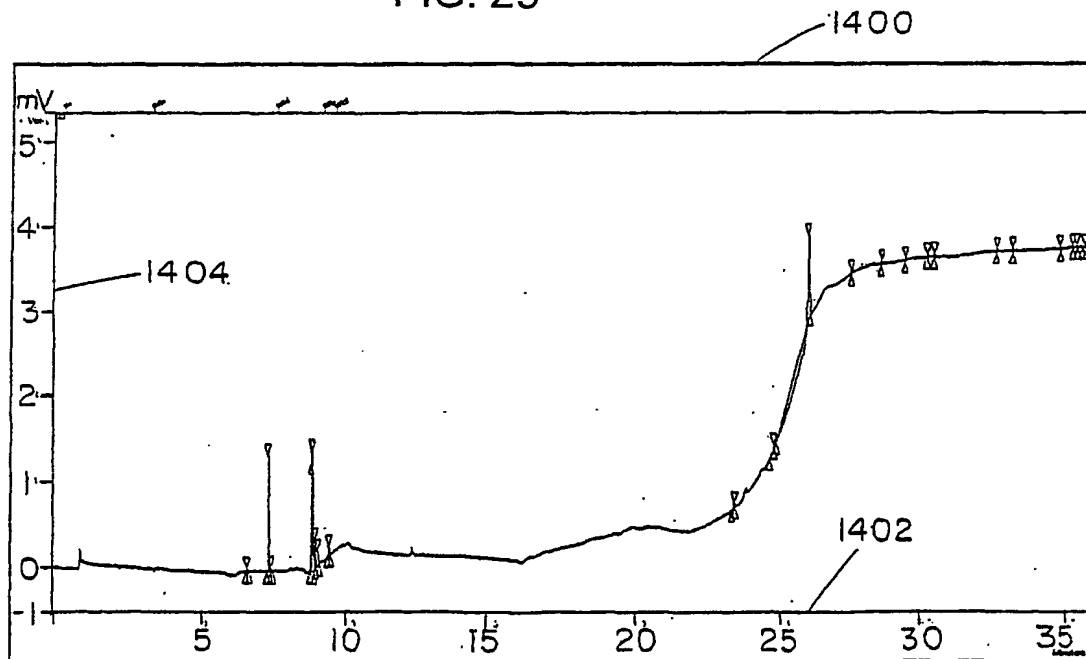


FIG. 30

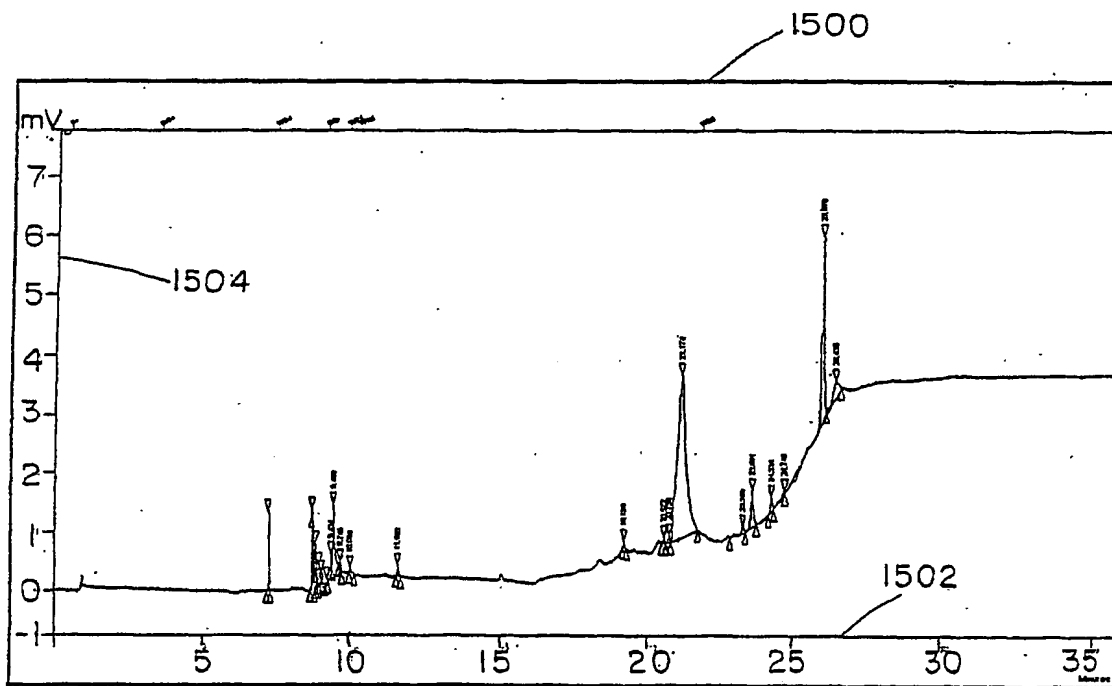


FIG. 31